



In re Application of:
Cheung, et al.

Serial No.: 10/648,616

Filed: August 26, 2003

Confirmation No.: 4378

For: Plasma Processes For
Depositing Low Dielectric
Constant Films

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Group Art Unit: Unknown

Examiner: Unknown

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING
37 CFR 1.8

I hereby certify that this correspondence is being deposited on 11/17, 2003 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

11/17/03 Kurt R. Zies
Date Signature

Dear Sir:

PRELIMINARY AMENDMENT

Prior to examination, please amend the above-identified application as follows. The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/3032.C6/KMT the fee of \$230.00 for 8 additional claims and 1 additional independent claim.

Amendments to the Specification begin on page 2. Amendments to the Claims begin on page 3. Remarks begin on page 7.

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01 FC:1201	86.00 DA
02 FC:1202	144.00 DA